

Miika Mattinen

List of Publications by Year in descending order

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papers

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430442

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#	ARTICLE	IF	CITATIONS
1	Atomic Layer Deposition of Crystalline MoS ₂ Thin Films: New Molybdenum Precursor for Low-Temperature Film Growth. <i>Advanced Materials Interfaces</i> , 2017, 4, 1700123.	1.9	98
2	Atomic Layer Deposition of Emerging 2D Semiconductors, HfS ₂ and ZrS ₂ , for Optoelectronics. <i>Chemistry of Materials</i> , 2019, 31, 5713-5724.	3.2	72
3	Atomic Layer Deposition of Rhenium Disulfide. <i>Advanced Materials</i> , 2018, 30, e1703622.	11.1	58
4	Atomic Layer Deposition of PbI ₂ Thin Films. <i>Chemistry of Materials</i> , 2019, 31, 1101-1109.	3.2	49
5	Low-Temperature Wafer-Scale Deposition of Continuous 2D SnS ₂ Films. <i>Small</i> , 2018, 14, e1800547.	5.2	48
6	Review Article: Atomic layer deposition of optoelectronic materials. <i>Journal of Vacuum Science and Technology B: Nanotechnology and Microelectronics</i> , 2019, 37, .	0.6	48
7	Scalable Route to the Fabrication of CH ₃ NH ₃ PbI ₃ Perovskite Thin Films by Electrodeposition and Vapor Conversion. <i>ACS Omega</i> , 2016, 1, 1296-1306.	1.6	44
8	Atomic layer deposition of crystalline molybdenum oxide thin films and phase control by post-deposition annealing. <i>Materials Today Chemistry</i> , 2018, 9, 17-27.	1.7	44
9	Atomic Layer Deposition of Photoconductive Cu ₂ O Thin Films. <i>ACS Omega</i> , 2019, 4, 11205-11214.	1.6	40
10	Atomic Layer Deposition of 2D Metal Dichalcogenides for Electronics, Catalysis, Energy Storage, and Beyond. <i>Advanced Materials Interfaces</i> , 2021, 8, 2001677.	1.9	39
11	Nucleation and Conformality of Iridium and Iridium Oxide Thin Films Grown by Atomic Layer Deposition. <i>Langmuir</i> , 2016, 32, 10559-10569.	1.6	31
12	Diamine Adduct of Cobalt(II) Chloride as a Precursor for Atomic Layer Deposition of Stoichiometric Cobalt(II) Oxide and Reduction Thereof to Cobalt Metal Thin Films. <i>Chemistry of Materials</i> , 2018, 30, 3499-3507.	3.2	27
13	Atomic Layer Deposition of Iridium Thin Films Using Sequential Oxygen and Hydrogen Pulses. <i>Journal of Physical Chemistry C</i> , 2016, 120, 15235-15243.	1.5	26
14	Atomic Layer Deposition of Molybdenum and Tungsten Oxide Thin Films Using Heteroleptic Imido-Amidinato Precursors: Process Development, Film Characterization, and Gas Sensing Properties. <i>Chemistry of Materials</i> , 2018, 30, 8690-8701.	3.2	26
15	Atomic Layer Deposition and Characterization of Bi ₂ Te ₃ Thin Films. <i>Journal of Physical Chemistry A</i> , 2015, 119, 2298-2306.	1.1	24
16	Atomic layer deposition of tin oxide thin films from bis[bis(trimethylsilyl)amino]tin(II) with ozone and water. <i>Journal of Vacuum Science and Technology A: Vacuum, Surfaces and Films</i> , 2017, 35, .	0.9	23
17	Rhenium Metal and Rhenium Nitride Thin Films Grown by Atomic Layer Deposition. <i>Angewandte Chemie - International Edition</i> , 2018, 57, 14538-14542.	7.2	21
18	Low-temperature atomic layer deposition of copper(II) oxide thin films. <i>Journal of Vacuum Science and Technology A: Vacuum, Surfaces and Films</i> , 2016, 34, .	0.9	18

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19	Van der Waals epitaxy of continuous thin films of 2D materials using atomic layer deposition in low temperature and low vacuum conditions. <i>2D Materials</i> , 2020, 7, 011003.	2.0	18
20	Atomic Layer Deposition of PbS Thin Films at Low Temperatures. <i>Chemistry of Materials</i> , 2020, 32, 8216-8228.	3.2	16
21	Crystalline tungsten sulfide thin films by atomic layer deposition and mild annealing. <i>Journal of Vacuum Science and Technology A: Vacuum, Surfaces and Films</i> , 2019, 37, .	0.9	15
22	Atomic Layer Deposition of Intermetallic Co ₃ Sn ₂ and Ni ₃ Sn ₂ Thin Films. <i>Advanced Materials Interfaces</i> , 2019, 6, 1801291.	1.9	15
23	Atomic layer deposition of lanthanum oxide with heteroleptic cyclopentadienyl-amidinate lanthanum precursor - Effect of the oxygen source on the film growth and properties. <i>Thin Solid Films</i> , 2018, 660, 199-206.	0.8	10
24	Controlling Atomic Layer Deposition of 2D Semiconductor SnS ₂ by the Choice of Substrate. <i>Advanced Materials Interfaces</i> , 2020, 7, 2001046.	1.9	10
25	Nickel Germanide Thin Films by Atomic Layer Deposition. <i>Chemistry of Materials</i> , 2019, 31, 5314-5319.	3.2	7
26	Selective etching of focused gallium ion beam implanted regions from silicon as a nanofabrication method. <i>Nanotechnology</i> , 2015, 26, 265304.	1.3	6
27	Atomic Layer Deposition of Nickel Nitride Thin Films using NiCl ₂ (TMPDA) and Tert-Butylhydrazine as Precursors. <i>Physica Status Solidi (A) Applications and Materials Science</i> , 2019, 216, 1900058.	0.8	6
28	Studies on solid state reactions of atomic layer deposited thin films of lithium carbonate with hafnia and zirconia. <i>Journal of Vacuum Science and Technology A: Vacuum, Surfaces and Films</i> , 2019, 37, .	0.9	5
29	Toward epitaxial ternary oxide multilayer device stacks by atomic layer deposition. <i>Journal of Vacuum Science and Technology A: Vacuum, Surfaces and Films</i> , 2019, 37, .	0.9	5
30	Atomic layer deposition of TbF ₃ thin films. <i>Journal of Vacuum Science and Technology A: Vacuum, Surfaces and Films</i> , 2021, 39, .	0.9	5
31	Atomic layer deposition of GdF ₃ thin films. <i>Journal of Vacuum Science and Technology A: Vacuum, Surfaces and Films</i> , 2022, 40, .	0.9	4
32	Atomic Layer Deposition of Zinc Glutarate Thin Films. <i>Advanced Materials Interfaces</i> , 2017, 4, 1700512.	1.9	3
33	Rhenium Metal and Rhenium Nitride Thin Films Grown by Atomic Layer Deposition. <i>Angewandte Chemie</i> , 2018, 130, 14746-14750.	1.6	3
34	Atomic Layer Deposition of Insulating AlF ₃ /Polyimide Nanolaminate Films. <i>Coatings</i> , 2021, 11, 355.	1.2	3
35	Atomic Layer Deposition of GdF ₃ Thin Films. <i>ECS Meeting Abstracts</i> , 2021, MA2021-02, 878-878.	0.0	1
36	Highly conductive and stable Co ₉ S ₈ thin films by atomic layer deposition: from process development and film characterization to selective and epitaxial growth. <i>Dalton Transactions</i> , 2021, 50, 13264-13275.	1.6	0